IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of: Bruno GHYSELEN

Application No.: Not Yet Assigned Group Art Unit: Not Yet Assigned

Filed: July 9, 2003 Examiner: Not Yet Assigned

For: METHOD FOR FABRICATING SUBSTRATES,

IN PARTICULAR FOR OPTICS, ELECTRONICS

OR OPTOELECTRONICS

INFORMATION DISCLOSURE STATEMENT

Attorney Docket No.: 4717-5600

Commissioner for Patents P.O. Box 1450 Alexandria, Virginia 22313-1450

Sir:

Pursuant to applicants' duty of disclosure under 37 C.F.R. 1.56, enclosed are copies of (11) references for the Examiner's review and consideration. These references are listed on the enclosed Form PTO-1449. A copy of a Preliminary Search Report in the counterpart French application is also enclosed.

It is respectfully requested that these references be made of record in this application by the Examiner's completion and return of Form PTO-1449.

No fee or certification is believed to be due for this submission since the references are being submitted concurrent with the filing of this application. Should any fees be required, however, please charge such fees to **Winston & Strawn** Deposit Account No. 501-814.

Respectfully submitted,

Allan A. Fanucci (Reg. No. 30,256)

WINSTON & STRAWN CUSTOMER NO. 28765

Enclosures (212) 294-3311

ATTY. DOCKET NO.: APPLICATION NO.: LIST OF REFERENCES CITED BY APPLICANT 4717-5600 Form PTO-1449 APPLICANT: (Use several sheets if necessary) Bruno GHYSELEN FILING DATE: GROUP: July 9, 2003 U.S. PATENT DOCUMENTS FILING DATE IF APPROPRIATE *EXAMINE CITE SUBCLASS DOCUMENT NUMBER DATE CLASS NAME 5,374,564 12/94 Bruel 437 24 5,877,070 3/99 Goesele et al. 438 458 438 527 6,429,104 8/02 Auberton-Herve FOREIGN PATENT DOCUMENTS TRANSLATION DOCUMENT NUMBER DATE COUNTRY CLASS SUBCLASS YES NO 2 681 472 3/93 France X 2 774 510 8/99 \mathbf{X} France X 0 610 563 A2 8/94 **EPC** X 10093122 4/98 Japan X WO 99/41779 8/99 **PCT PCT** X WO 00/61841 10/00 X WO 01/75196 10/01 PCT (with English-language Abstract) OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.) M.K. Weldon, et al. - Mechanism of Silicon Exfoliation by Hydrogen Implantation and He, Li and Si Co-implantation - IEEE International SOI Conference, October 1997.

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

DATE CONSIDERED

EXAMINER